Low Energy Electron Induced Decomposition of Adsorbed Methylcyclopentadienylplatinum(IV)trimethyl



American Vacuum Society 55th Annual Meeting Boston, Massachusetts

Joshua D. Wnuk Johns Hopkins University Baltimore, MD, USA

Outline

- Background / Motivation
- Experimental Approach
- Surface Chemistry and Kinetics
- Summary

Electron Beam Induced Deposition



The ability to focus electron beams into small spots, control electron beam fluence and raster the beam makes EBID an ideal method for growing a wealth of different nanostructures

Examples of EBID

Freestanding Pt wire grown from MeCpPtMe₃



Frabboni et al., Physica E, 2007, 265.

Pt wire, $4\mu m$ long, grown between Au electrodes on Si / SiO₂ substrate from MeCpPtMe₃



Botman et al., Nanotechnology, 2006, 3779.

Pt wire grown on SiO₂ from MeCpPtMe₃



Gopal et al., Appl. Phys. Lett., 2005, 49.



Cicoira et al., J. Cryst. Growth, 2004, 619.

Motivation

The fundamental surface processes that are responsible for electron beam induced deposition of nanostructures are not well understood

- Many questions about EBID process
 - Chemical reactions at the surface?
- •If we can better understand the chemistry, we can:
 - Choose precursors more selectively
 - Improve deposition purity (carbon)
 - Improve purification techniques
 - Increase metallic characteristics

Outline

- Background / Motivation
- Experimental Approach
- Surface Chemistry and Kinetics (500eV)
- Summary

Our Approach

- To understand the EBID process using well established surface analytical techniques
 - Adsorbing a nanometer scale film of EBID precursor to a substrate provides a "clean" environment for *in situ* observation
 - Surface coverage can be controlled
 - An UHV environment enables analysis of gas phase products
 - A film, on the order of cm² in area, can be analyzed using common surface analytical techniques

Broad Beam Surface Irradiation



Instrumental Techniques



• We have studied the electron stimulated reactions of the wellknown Pt precursor, Trimethyl(methylcyclopentadienyl)platinum(IV), adsorbed onto gold using the above techniques:

Outline

- Background / Motivation
- Experimental Approach
- Surface Chemistry and Kinetics (fixed electron energy = 500eV)
- Summary

RAIRS Analysis of Dissociation Kinetics

•Time resolved *in situ* RAIRS analysis shows loss of v(C-H) intensity with increasing electron beam irradiation



Adsorption of MeCpPt(IV)Me₃ onto Gold Substrate – Controlling film thickness



Production of Amorphous Platinum/Carbon Film



XP spectra of sputter deposited platinum on gold

Substrate heated to room temperature leaving electron beam irradiation product

Electron beam irradiation for 20 sec (20µA, 500eV)

MeCpPt(IV)Me₃ adsorbed onto gold substrate (~195K)



----- Au





Influence of e⁻ Beam Irradiation on Surface Composition of Adsorbate Layer



XPS Analysis of Dissociation Kinetics



Quantification of the deconvoluted Pt(4f) region fit to exponential decay shows first order kinetics

Decay profiles show that the observed rate constant increases with increasing target current.

Signal Resolution vs. Signal Intensity



Carbon Loss During Irradiation



• The C:Pt ratio of 10 XP spectra of the MeCpPt(IV)Me₃ prior to e⁻ beam irradiation is representative of the initial stoichiometric ratio of 9 carbon atoms to 1 platinum atom The stoichiometric loss of 1

• The C.Pt ratio after e beam irradiation decreases independent of indicating the beam of the strong of the strong



Gas Phase Products Analysis



Kinetic Analysis of Methane Production



•Tracking methane production during electron beam irradiation fit to exponential decay

•m/z = 15 is a unique mass representative of methane

•Methane loss fit to first order kinetics indicates an increase in the observed rate constant with increasing target current

Dissociation by Pt-CH₃ Cleavage



Analogous compound decomposes via production of identical gas phase products

Complementary Techniques



$$\sigma = \frac{k_{obs}}{I_{target}} \times A$$

	(σ) cm²
XPS	1.37E-16
RAIRS	4.32E-16
MS (MeCpPtMe ₃)	9.75E-17
MS (CpPtMe ₃)	1.02E-16

 $\sigma_{\text{ave, 500eV}}$ = 2.2 E-16 cm²

XPS, RAIRS, and MS provide comparable σ values though they measure different processes

Outline

- Background / Motivation
- Experimental Approach
- Surface Chemistry and Kinetics (500eV)
- Summary



•Electron beam irradiation of surface adsorbed $MeCpPt(IV)Me_3$ results in the formation of platinum atoms embedded in an amorphous carbon film via an electron impact process in which bond cleavage releases hydrogen and methane.

•Each precursor molecule that undergoes electron stimulated decomposition losses exactly one carbon atom.

A UHV surface science approach can provided valuable information on reaction rates and fundamental chemical processes involved in EBID

Acknowledgements

- Howard Fairbrother, Johns Hopkins University
- Justin Gorham, Johns Hopkins University
- Willem van Dorp, Rutgers University
- Ted Madey, Rutgers University
- Kees Hagen, Delft University of Technology

Thank you

Solution to Au satellites





Electron Source: Flood Gun

- Why use a flood gun?
 - Uniform electron beam over a wide area (necessary for XPS and RAIRS)
 - High target current
 - Relatively broad range of Energies (40 500eV)



Electron Flood Gun can produce: (a) 40 - 500 eV electrons (b) 5 -150 μA target currents

Sample



(100K-450K)

X-ray Photoelectron Spectroscopy (XPS)



Reflection Absorption Infrared Spectroscopy (RAIRS)



Mass Spectrometry (MS)

